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最終頁に続く

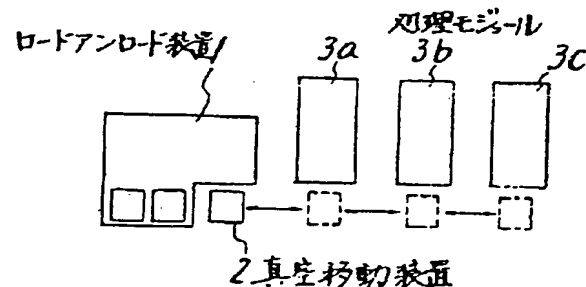
(54) 【発明の名称】 複数処理装置

(57) 【要約】

【課題】 各処理室の相互汚染がなく、保守性が良い連続で複数の処理が行える複数真空処理装置を得る。

【解決手段】 試料を処理開始から終了まで、又は一つ以上の処理の間、真空に保持し、複数の真空室で処理を行う装置であって、真空室の試料の移動を、真空室を移動および結合できる真空室を介して行う。

図 1



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(71)Applicant : HITACHI LTD

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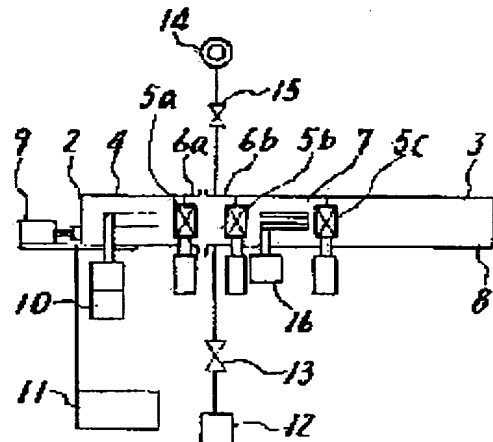
(54) A PLURALITY OF PROCESSORS

(57)Abstract:

PROBLEM TO BE SOLVED: To make feasible of a plurality of continuous processings in excellent maintainability avoiding the mutual pollution in respective processing chambers by communicating the specimens in carrying in and out possible mode between a closed vessel and an arbitrary one processing module by opening a first and a second opening and closing parts.

SOLUTION: In respective processing modules 3, a vacuum chamber is formed of a specimen processing chamber 8, a vacuum holding buffer chamber 7 containing a carrier arm 16 as well as a lock chamber 6b connecting to another lock chamber 6a of a vacuum moving device 2 while respective chambers are communicated with gate valves 5b, 5c. The lock chamber 6b is connected to an N₂ gas source 14 for restoring the lock chambers 6a and 6b to atmospheric air through the intermediary of a valve 15. Besides, a vacuum pump 12 is connected to the lock chamber 6b through the intermediary of another valve 13 for vacuumizing.

Furthermore, a load unload device 1 is provided with the same structure as that of the processing modules 3. Through these procedures, the problem of mutual pollution between respective vacuum chambers is settled while respective processing modules are separated, thereby enabling the maintainability of the processors to be enhanced.



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